SEMICAPS 4000

INVERTED ANALYTICAL AND TESTER-DOCKED SYSTEM





Features

- Analytical or ATE docked configuration
- 300 mm wafer stage including auto-lock compatible with Probe Cards and manipulators
- Docks easily to Tester or Probe Station
- High resolution stage with 0.5 μm repeatability
- Aplanatic Refractive Solid Immersion Lens (ARSIL) option, currently probing <u>3nm nodes</u>
- CAD interface option
- Analysis Methodologies include a combination of:
 - Laser Timing Probe (LTP)
 - Scanning Optical Microscopy (SOM) with best sensitivity for

static analysis: TIVA, OBIRCH dynamic analysis: LADA, SDL

- Photon Emission Microscopy (PEM) with various options for the InGaAs or Si-CCD camera
- Thermal Microscopy (THM)

